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PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant : Weimin Li et al.  
Appl. No. : 10/757,638  
Filed : January 13, 2004  
For : TECHNIQUE FOR HIGH  
EFFICIENCY METALORGANIC  
CHEMICAL VAPOR  
DEPOSITION  
Examiner : Michael K. Luhrs  
Group Art Unit : 2824

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

October 29, 2004

(Date)

Linda H. Liu, Reg. No. 51,240

**AMENDMENT**

**Mail Stop Amendment**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

The Applicant respectfully submits the following amendments and remarks in response to the Office Action mailed July 29, 2004.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 4 of this paper.